Search Notes

Application/Control N	No. Applicant(s)/Patent Reexamination	under
10/655,942	HASEGAWA, NAO	YA
Examiner	Art Unit	
Paul D. Kim	3729	

	SEARCHED				
Class	Subclass	Date	Examiner		
29	603.07 603.08 603.11- 603.16	2/22/2006	PK		
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)				
	DATE	EXMR		
Reviewed Parent Aplication 09/905,330 (US PAT. 6,751,073)`	2/22/2006	PK		
Text Search EAT/NPL (IEEE)	2/23/2006	PK		
Updated Text Search EAST				